
Harnessing The Micro Revolution:

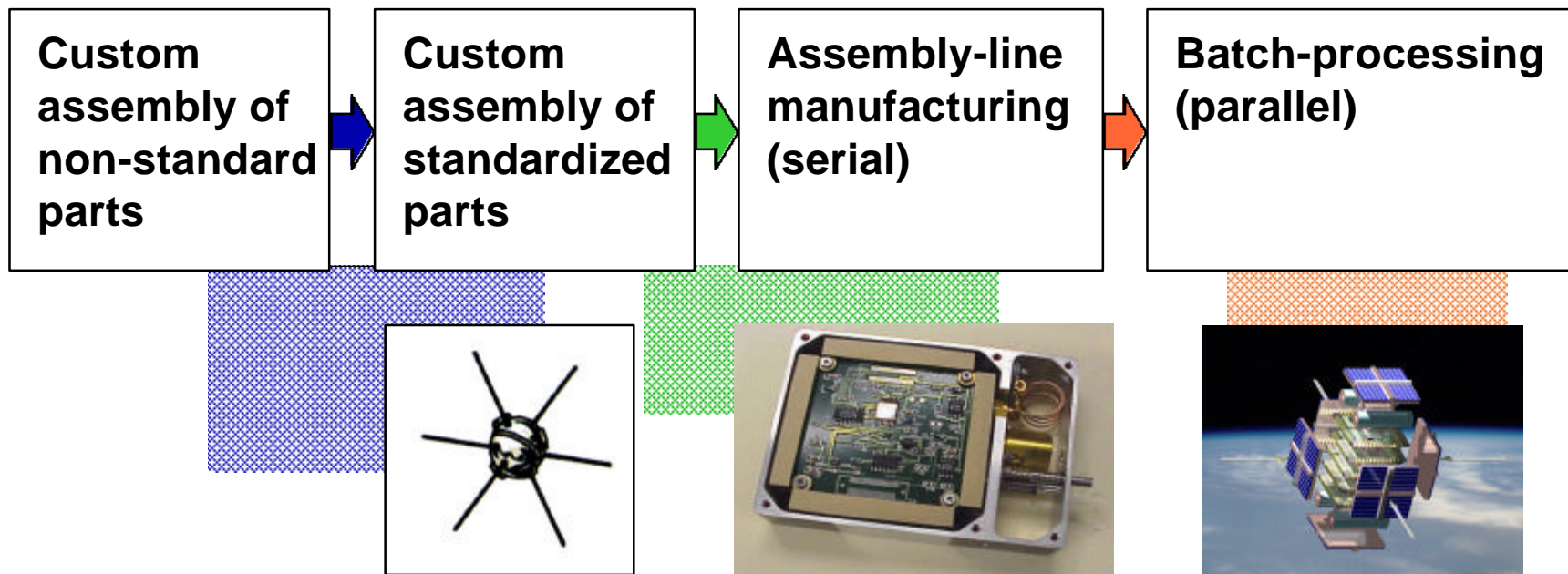
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Center for Microtechnology,
The Aerospace Corporation
El Segundo, California (USA)

August 11, 1999

A “Micro” Revolution for Spacecraft

The Evolution of Manufacturing:



| | | | |
|-----------------------------|------------|---------------|-------------------------|
| Small Spacecraft: | Vanguard 1 | DARPA PICOSAT | “Integrated” Satellites |
| Launch Year: | 1958 | 1999 | ~2005 |
| Functional Elements: | ~100 | ~100,000 | ~100,000,000 |

Microelectronics: The Evolution of a Revolution

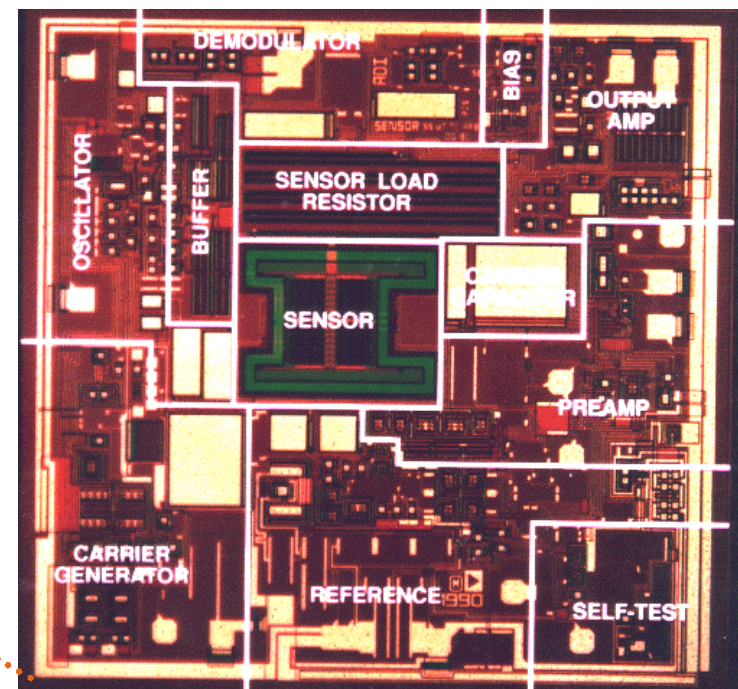
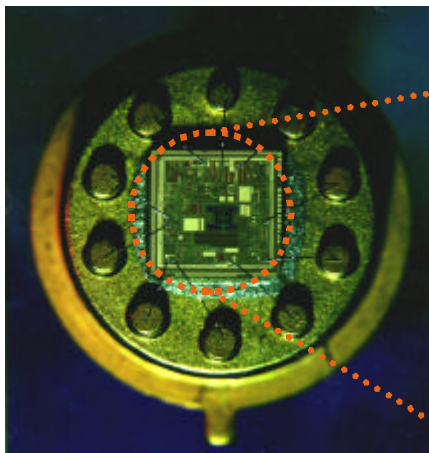
| Year: | Smallest Feature (microns) | Dynamic RAM: | | Microprocessors: | |
|-------|----------------------------|-----------------------------|---------------------------|-----------------------------|---|
| | | Die Size (cm ²) | Billions of Bits per Dice | Die Size (cm ²) | Millions of Transistors per cm ² |
| 1995 | 0.35 | 1.9 | 0.064 | 2.5 | 4 |
| 1998 | 0.25 | 2.8 | 0.256 | 3.0 | 7 |
| 2001 | 0.18 | 4.2 | 1 | 3.6 | 13 |
| 2004 | 0.13 | 6.4 | 4 | 4.3 | 25 |
| 2007 | 0.10 | 9.6 | 16 | 5.2 | 50 |
| 2010 | 0.07 | 14 | 64 | 6.2 | 90 |

The microelectronics “revolution” continues along a predictable path

From “Technology 1996: Solid State”, *IEEE Spectrum*, 33 #1, p. 51-55, January 1996

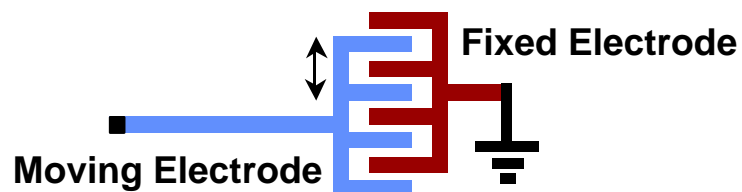
A REVOLUTION IN MECHANICAL CONSTRUCTION: MICROELECTROMECHANICAL SYSTEMS (MEMS)

Analog Devices ADXL50 Accelerometer



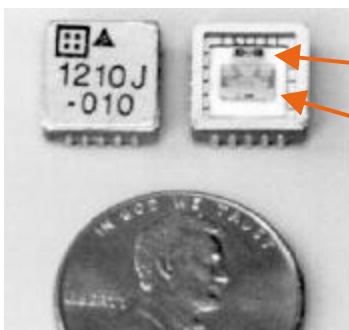
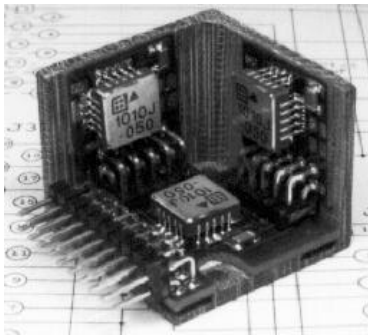
3 millimeters

Principle of operation:

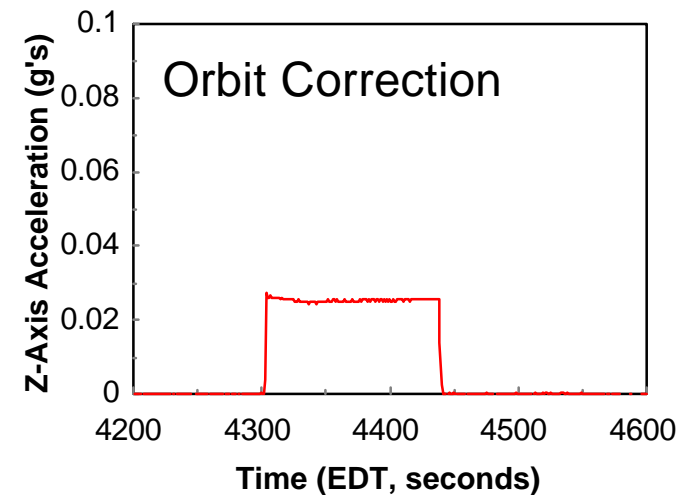
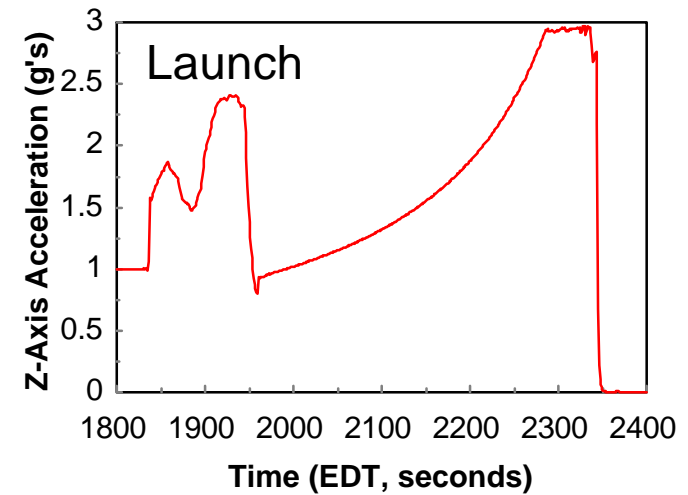


MEMS Accelerometers Monitored STS-93 Flight

**Silicon Designs 1010J & 1210J
Capacitive MEMS Accelerometers**



**Sensor
ASIC**



Why MEMS Are An Enabling Technology

- **You can simultaneously fabricate thousands of devices**
 - Micron-to-millimeter scale machines
 - Coordinated primitive functions by multiple devices can produce complex functions (like a computer!)
- **Integrated electronics can be co-manufactured**
 - Increased signal-to-noise ratios for sensors due to reduced parasitic loads
 - You can produce “smart” sensors and actuators for high reliability
- **Reduced size and power requirements for sensors**
- **Traditional off-chip components can be made on-chip**
 - High frequency inductors, bandpass filters, etc.

Possible MEMS Insertion Into Spacecraft Systems:

Command and Control Systems:

- ➡ -“MEMtronics” for ultra-radiation-hard and temperature-insensitive logic

Inertial Guidance Systems:

- ➡ - Microgyros and microaccelerometers
- Micromirrors and microoptics for FOGs (fiber optic gyros)

Attitude Determination and Control Systems:

- Micromachined sun and Earth sensors
- Micromachined magnetometers

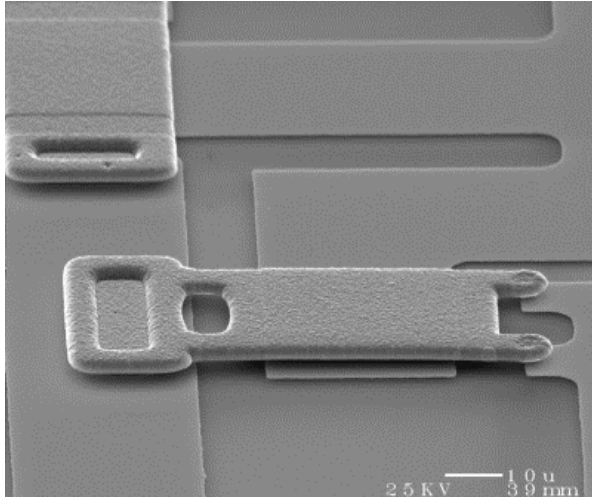
Propulsion Systems:

- Micromachined pressure and chemical sensors
- ➡ - Arrays of single-shot thrusters (“digital propulsion”)
- Continuous or pulsed microthrusters

Communications and Radar Systems:

- Very high bandwidth, low power, low resistance rf switches
- ➡ - Micromirrors and microoptics for laser communications

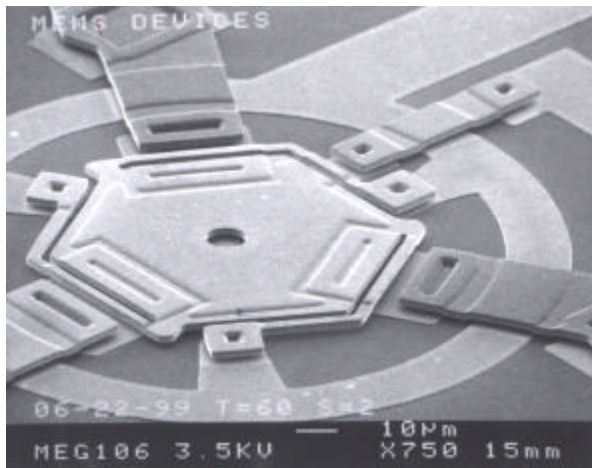
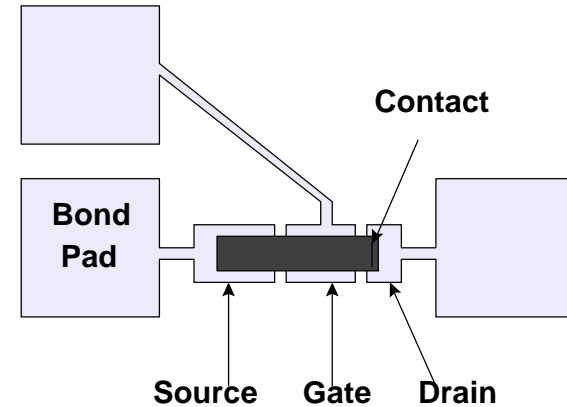
MEMS Switches: RF, Digital, or Analog



From:
P.M. Zavracky et al.,
“Micromechanical Switches
Fabricated Using Nickel
Surface Micromachining,” *J. Microelectromechanical
Systems*, 6 #1, March 1997

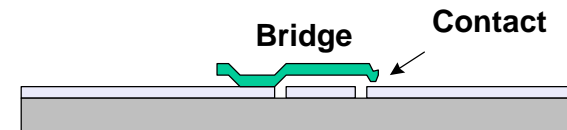
<http://www.ece.neu.edu/edsnu/zavracky/mfl/programs/relay/relay.html>

Top View:



From:
Aerospace Corp.

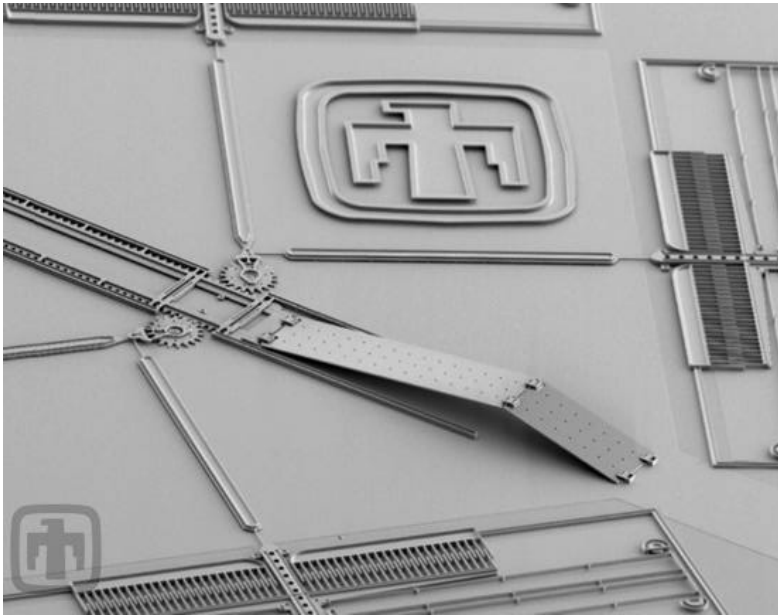
Side View:



- ***Super radiation-hard,***
- ***Wide operating temperature range***
- ***Low insertion loss***
- ***Wide bandwidth***

Optical MEMS Devices for Possible Space Applications

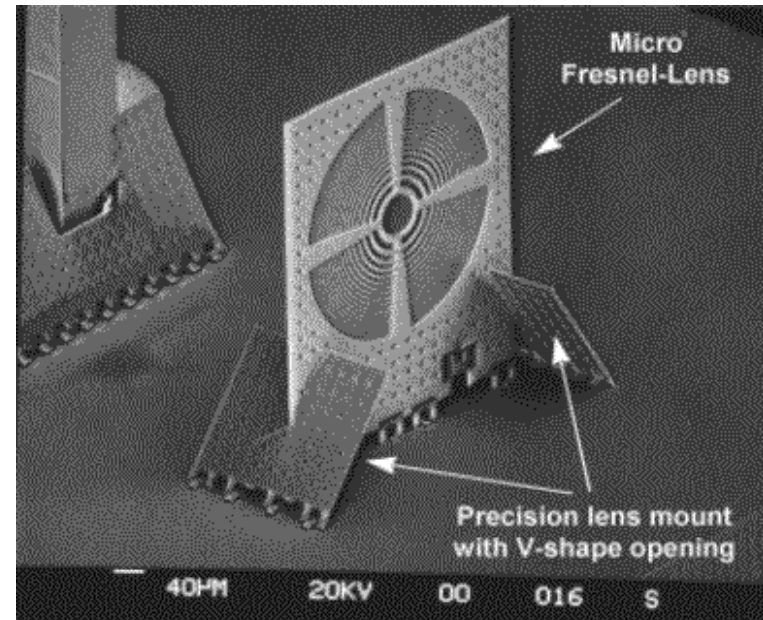
MEMS “Pop Up” Mirror (Sandia)



<http://www.mdl.sandia.gov/micromachine/images6.html>

See also: “Optics & MEMS” by S.J. Walker and D.J. Nagel, <http://code6330.nrl.navy.mil/6336/moems.htm>

MEMS “Pop Up” Lens (UCLA)



M.C. Wu, “Micromachining for Optical and Optoelectronic Systems,” Proc. IEEE, Vol. 85, #11, Nov 1997; <http://www.ee.ucla.edu/labs/laser/research/mot/1integrated.html>

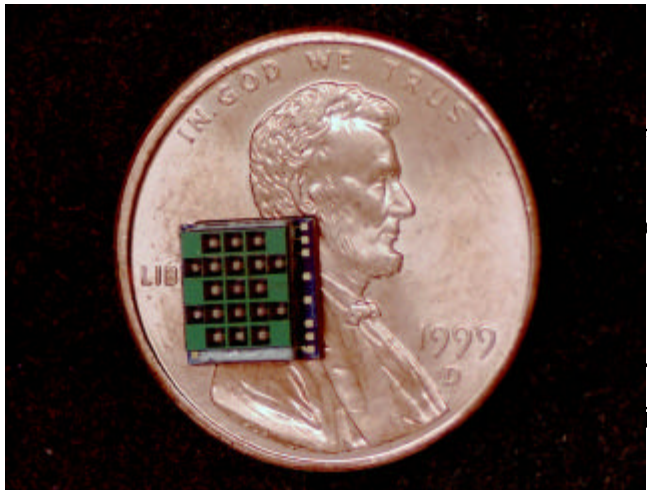
MEMS Thrusters and Components



MTO

MEMS

15-Thruster "Chip" on STS-93

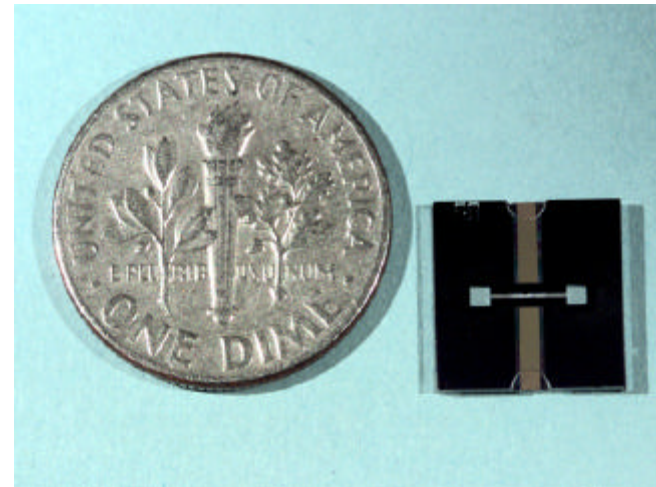


<http://www.design.caltech.edu/micropropulsion/index.html>

TRW, CalTech, and The Aerospace Corp.



Micro Isolation Valve



J. Mueller, S. Vago, D. Bame, D. Fitzgerald, and W. Tang," Proof-of-Concept Demonstration of a Micro-Isolation Valve," AIAA paper 99-2726, June 1999

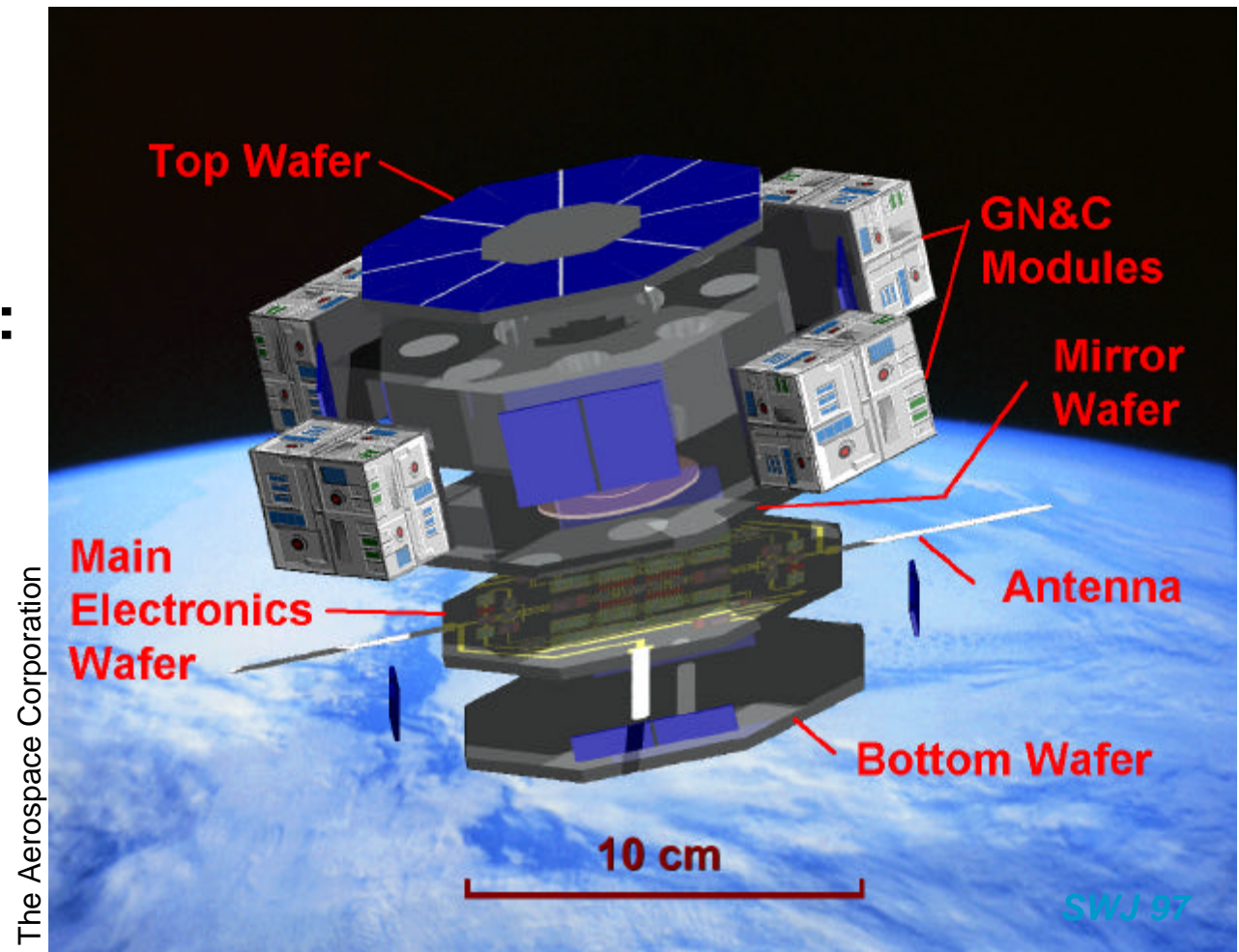
21st Century Micro/Nano/Picosatellites

- **Highly-integrated designs**
 - More functional elements, fewer piece-parts
 - Integrated diagnostics, self-test, and reconfiguration
 - “Silicon satellites”; grams-to-kilograms in mass
- **Batch or assembly-line fabrication in large lots (>100)**
 - Virtual satellites, e.g., km-scale sparse aperture arrays
 - Disposable satellites, e.g., satellite inspectors
 - Dense constellations for continuous Earth coverage
- **“Two-dimensional” satellites**
 - Large aperture/weight ratios, e.g., TechSat-21

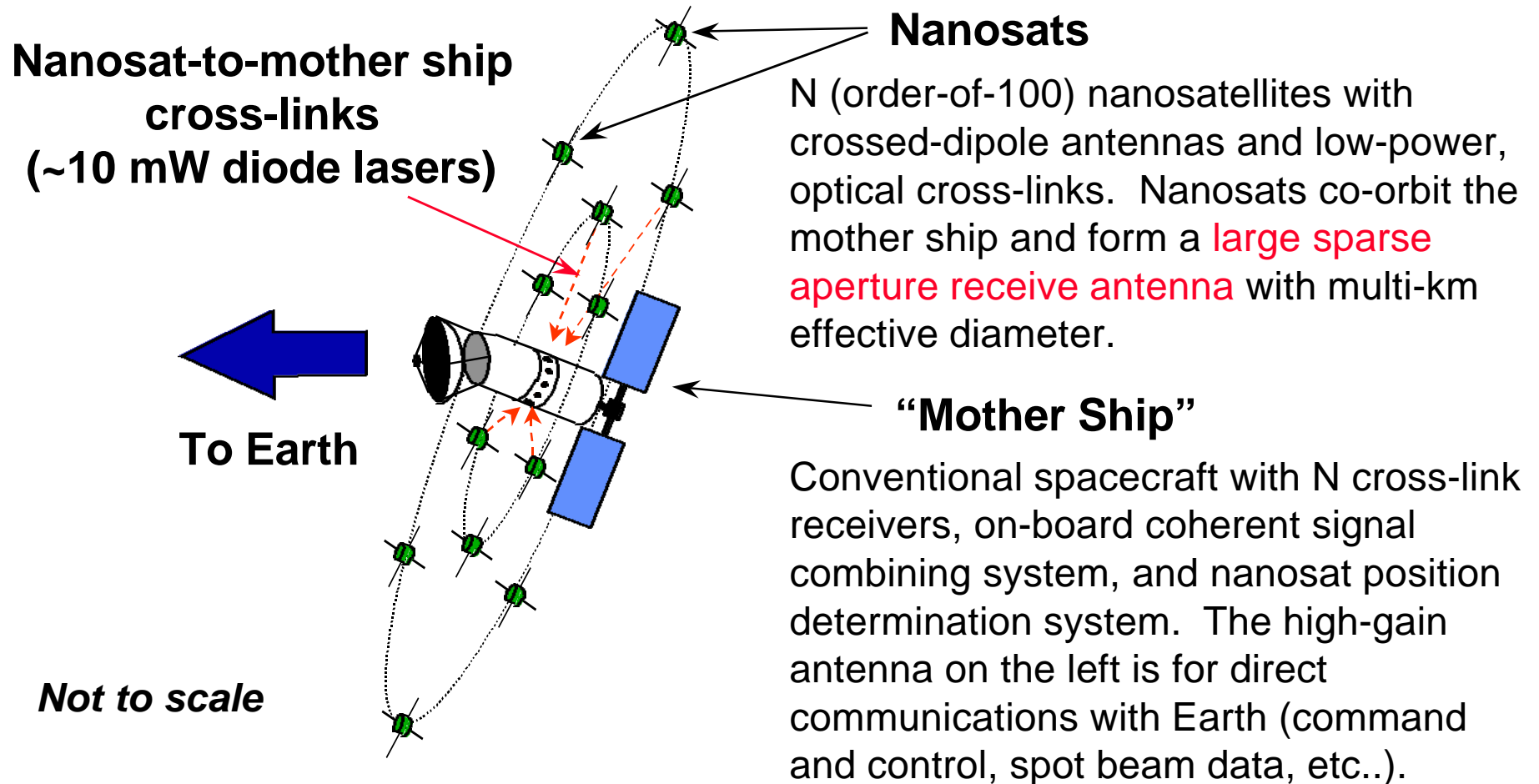
A Silicon Nanosatellite Concept

Silicon serves as:

Structure,
Radiation shield,
Thermal control,
Optical material,
MEMS substrate,
Electronic substrate



Nanosatellite Sparse Array Antenna Concept

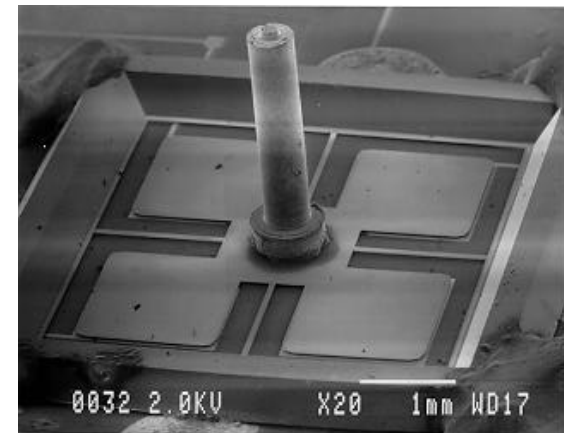


Relevant R&D Activity (U.S.)

- **MEMS for space applications**

- AFRL, AFOSR, DARPA
- Sandia National Laboratories
- NASA-JPL, NASA-Glenn
- TRW, Draper Laboratories, Honeywell, Marotta Scientific, Hughes, Rockwell Science Center,...
- CalTech, MIT, U.C. Berkeley, UCLA, ...

NASA-JPL Microgyro



<http://csmt.jpl.nasa.gov/mgyro.html>

- **Integrated Micro/Nanospacecraft**

- AFRL (TechSat-21)
- NASA-JPL (X-2000 Deep Space Systems Technology Program)
- Sandia (Nanosatellite)
- NASA-Goddard (Nanosatellites for magnetospheric mapping)

Summary:

- **MEMS and microtechnology can enable small, lightweight, but sophisticated spacecraft for challenging missions**
- **Mass-produced, integrated spacecraft can enable new space missions such as km-scale virtual spacecraft**
- **Spacecraft design and space architectures may radically change during the next decade**